

|   |                 |   |         | ATTY. DOCKET NO.:           |          | APPLICATION NO.:              |    |  |
|---|-----------------|---|---------|-----------------------------|----------|-------------------------------|----|--|
|   |                 |   |         | 4717-6100                   |          | 10/664781                     |    |  |
|   |                 |   |         | APPLICANT:                  |          |                               |    |  |
|   |                 |   |         | Christophe MALEVILLE et al. |          |                               |    |  |
|   |                 |   |         | FILING DATE:                |          | GROUP:                        |    |  |
|   |                 |   |         | 9/16/2003                   |          | 1746                          |    |  |
| <b>U.S. PATENT DOCUMENTS</b>  |                 |   |         |                             |          |                               |    |  |
| *EXAMINER<br>INITIAL  | DOCUMENT NUMBER | DATE  | NAME    | CLASS                       | SUBCLASS | FILING DATE IF<br>APPROPRIATE |    |  |
| b5c   | AA              | 5,158,100   | 10/1992 | Tanaka et al.               | 134      | 105                           |    |  |
|   | AB              | 5,232,870   | 8/1993  | Ito et al.                  | 437      | 173                           |    |  |
|   | AC              | 5,727,578   | 3/1998  | Matthews                    | 134      | 61                            |    |  |
|   | AD              | 5,776,296   | 7/1998  | Matthews                    | 156      | 345                           |    |  |
|   | AE              | 6,240,933 B1  | 6/2001  | Bergman                     | 134      | 1.3                           |    |  |
|   | AE              | 6,273,108 B1  | 8/2001  | Bergman et al.              | 134      | 102.1                         |    |  |
|   | AF              | 2002/0050279 A1   | 5/2002  | Bergman                     | 134      | 3                             |    |  |
|   | AG              | 2002/0066464 A1   | 6/2002  | Bergman                     | 134      | 1                             |    |  |
| b6d   | AH              | 2002/0157686 A1   | 10/2002 | Bergman                     | 134      | 1.3                           |    |  |
| <b>FOREIGN PATENT DOCUMENTS</b>   |                 |   |         |                             |          |                               |    |  |
|   | DOCUMENT NUMBER | DATE  | COUNTRY | CLASS                       | SUBCLASS | TRANSLATION                   |    |  |
|   |                 |   |         |                             |          | YES                           | NO |  |
| b5c   | AI              | EP 0 476 897 A2   | 3/1992  | Europe                      |          |                               | X  |  |
|   | AJ              | EP 0 731 495 A2   |         | Europe                      |          |                               | X  |  |
|   | AK              |   |         |                             |          |                               |    |  |
| <b>OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)</b>  |                 |   |         |                             |          |                               |    |  |
| b5c   | AL              | Kaneko et al., "Low Temperature Silicon Surface Cleaning by HF Etching/Ultraviolet Ozone Cleaning (HF/UVOC) Method (II)- in situ UVOC", Journal of Applied Physics, Vol. 28, No. 12, pp. 2425-2429 (1989) |         |                             |          |                               |    |  |
|   | AM              |   |         |                             |          |                               |    |  |
|   | AN              |   |         |                             |          |                               |    |  |
|   | AO              |   |         |                             |          |                               |    |  |
| <b>EXAMINER</b>   |                 |   |         | <b>DATE CONSIDERED</b>      |          |                               |    |  |
| S. C. Lee   |                 |   |         | 8/11/04                     |          |                               |    |  |
| <p><small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small></p> |                 |   |         |                             |          |                               |    |  |